

FORM PTO 1449 (modified)

U.S. DEPARTMENT OF COMMERCE
PATENT AND TRADEMARK OFFICELIST OF REFERENCES CITED BY APPLICANT(S)
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Yutaka NANNO et al.FILING DATE
December 21, 2001

GROUP

U.S. PATENT DOCUMENTS

*EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
<i>SK</i>	5,308,998	05/03/1994	Yamazaki et al.			
<i>SK</i>	5,686,328	11/11/1997	Zhang et al.			
<i>SK</i>	5,977,559	11/02/1999	Zhang et al.			

FOREIGN PATENT DOCUMENTS

DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION NO	YES
<i>SK</i> 05-072555	03/26/1993	Japan (English abstract)			x	
<i>SK</i> 10-293322	11/04/1998	Japan (English abstract)			x	
<i>SK</i> 05-136417	06/01/1993	Japan (English abstract only)			x	
<i>SK</i> 05-053148	03/05/1993	Japan (English abstract only)			x	
<i>SK</i> 05-088644	04/09/1993	Japan (English abstract only)			x	
<i>SK</i> 08-171101	07/02/1996	Japan (English abstract only)			x	
<i>SK</i> 05-289103	11/05/1993	Japan (English abstract only)			x	
<i>SK</i> 05-150260	06/18/1993	Japan (English abstract only)			x	
<i>SK</i> 09-146119	06/06/1997	Japan (English abstract only)			x	
<i>SK</i> 03-034434	02/14/1991	Japan (English abstract only)			x	
<i>SK</i> 06-224220	08/12/1994	Japan (English abstract only)			x	

OTHER DOCUMENT(S) (Including Author, Title, Date, Pertinent Pages, Etc.)

<i>SK</i>	Furuta, M., et al. "Diagonal Low-Temperature-Processed Poly-Si TFT-LCD with a New LDD Structure." Euro Display '96, pp. 547-550.
<i>SK</i>	Nanno, Yutaka, et al. "Analysis of Photo Induced Current of Low Temperature p-Si TFT." Matsushita Electric Industrial Co., Ltd., Display Devices Development Center. 3-1-1 Yagumo-Nakamachi, Moriguchi, Osaka 570-8501, Japan. <i>Date ?</i>
<i>SK</i>	Bae, B.S., et al. "New Poly-Si TFT Structure for OFF-Current Reduction." SID 96 DIGEST, pp. 25-28.
<i>SK</i>	Young, N.D., et al. "AMLCDS and Electronics on Polymer Substrates." Euro Display '96, pp. 555-558.
<i>SK</i>	Edwards, M.J., et al. "Laser Crystallised Poly-Si Circuits for AMLCDs." ASIA DISPLAY '95, pp. 335-337.

EXAMINER

Shousang Liu

DATE CONSIDERED

4/30/03

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

*: not considered, as no date is provided for it.